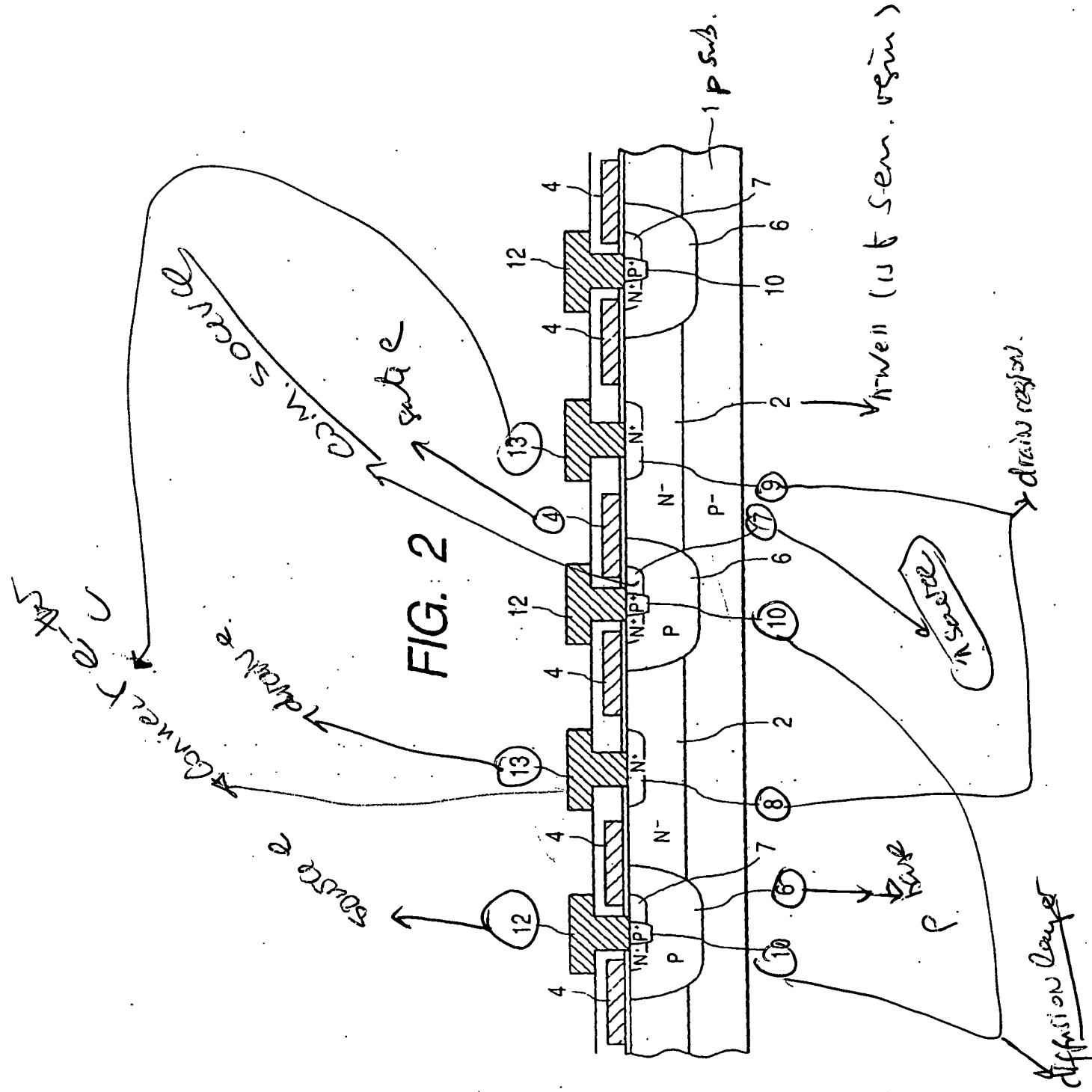


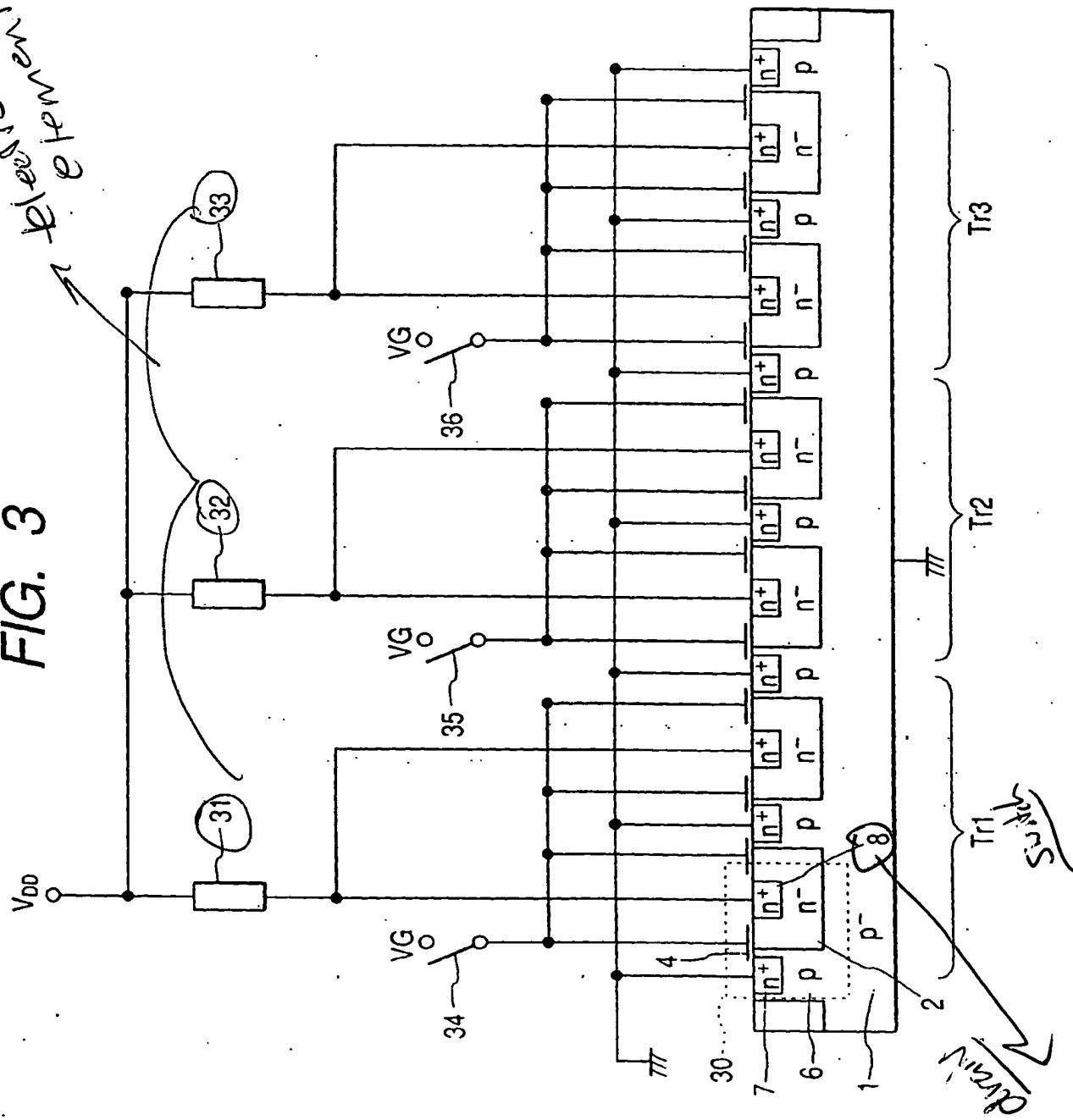
2 / 34



3 / 34

Conv
has
elec
elements
at a
look

FIG. 3



6 / 34

FIG. 6A

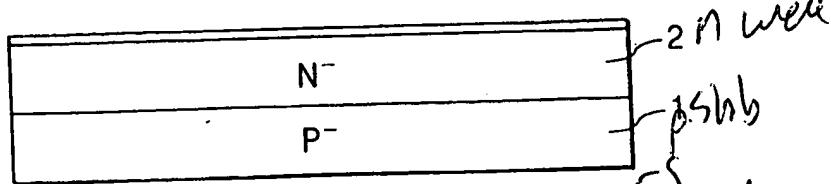


FIG. 6B

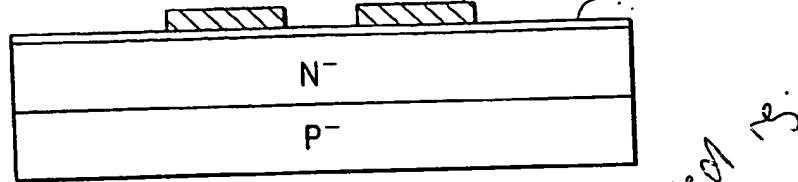


FIG. 6C

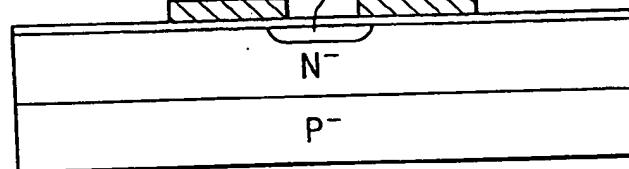


FIG. 6D

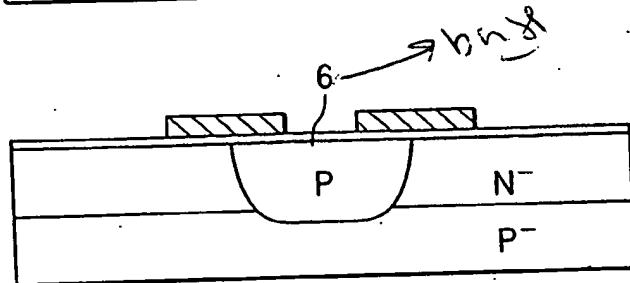


FIG. 6E

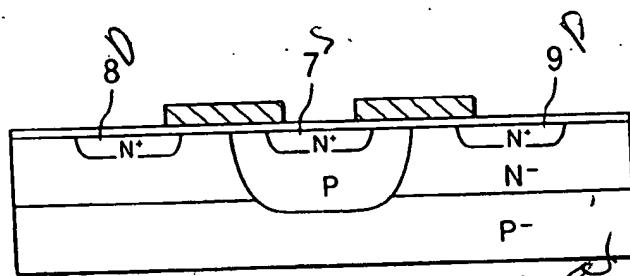
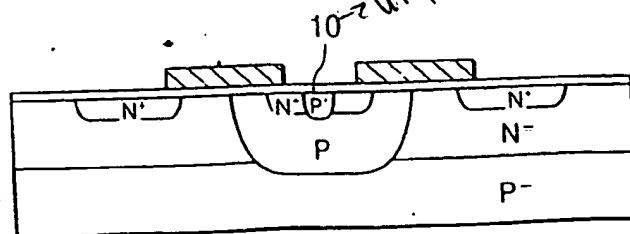


FIG. 6F



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recorded head

tantalum nitride heat resistor layer

160

150

plenty

FIG. 38

120

104

180

170

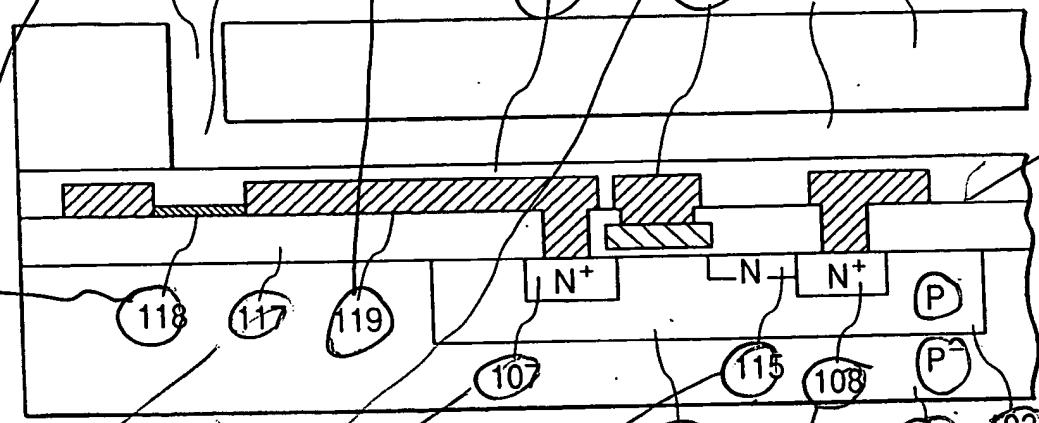
aluminum alloy film wiring

Si protective film

gate.

electro-thermal
conversion
element

switching

Si oxide as thermal
storage layer
n source

n field relaxation drain?

n drain

p substrate

MIS